

b) Amendments to the Specification

Please substitute the paragraph beginning at page 15, line 22 and ending at page 16, line 11 with the following replacement paragraph.

--Figs. 1A and 1B illustrate an example of the construction of a deposited-film formation apparatus according to the present invention. In Figs. 1A and 1B, reference numeral 101 denotes a temperature sensor ; 102, first evacuation piping; 103, downstream-side second evacuation piping; 104, a flange joint as a piping connection part; 105, deposited-film-forming chamber; 106, a vacuum pump as the evacuation means; 107, an exhaust gas treatment apparatus; 108, a high-frequency power source; 110, a gas introducing pipe; 111 to 114, gas flow meters; 115 to 118, valves; 119, electrodes; and 120, an aluminum tape. A thermocouple is used as the temperature sensor 101. The temperature sensor 101 is attached to the outer surface of the piping 103 in good contact so that the temperature of the evacuation piping 103 extending from the vacuum pump 106 to the exhaust gas treatment apparatus can be measured.--

Please substitute the paragraph beginning at page 27, line 25 and ending at page 28, line 10 with the following replacement paragraph.

--In the apparatus shown in Figs. 6A and 6B, the main part of the apparatus and the exhaust gas treatment apparatus 107 are provided at a large distance, and part of the evacuation piping 603; extending between the vacuum pump 106 and the exhaust gas treatment apparatus 107, is installed outdoors. This evacuation piping 603 is provided at its part exposed to the outdoor, with the sight glass window 622 as another kind of piping connection part so that its interior can be observed. The thermocouple 601 is provided at a

position on 10 cm downstream side of the sight glass window 622. Also, the thermocouple 601 and its surrounding piping are kept covered with the heat insulator 623.--